

re the Application of: TANIGUCHI, Osamu et al.

Group Art Unit: 2823

Serial No.: 10/084,923

Examiner: William M. BREWSTER

Filed: March 1, 2002

P.T.O. Confirmation No.: 7126

FOR: THIN-FILM CIRCUIT SUBSTRATE AND MANUFACTURING METHOD THEREOF, AND A VIA FORMED SUBSTRATE AND MANUFACTURING METHOD **THEREOF**

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents Washington, D.C. 20231

Date: April 4, 2003

Sir:

This paper is submitted in response to the Official Action dated March 21, 2003.

In the Action, restriction is required between Group (I), Claims 1-10 and 17-22; and Group (II), Claims 11-16 and 23-29.

Applicants hereby elect the subject matter of Group (I), Claims 1-10 and 17-22 for natter under 35 USC 120 and 35 USC 121 are retained.

In the event that this paper is not timely filed, applicants hereby petition for an appropriate extension of time. The fee for any such extension may be charged to our Deposit No. 01-2340. prosecution in this application. This election is made without traverse, it being understood that the applicants' rights to the filing of a divisional application directed to the non-elected subject

In the event any additional fees are required in connection with this response, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

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